ranamentary Advanced Studies Institute

(1.2.11) As Sambache, Pulagonia, Alternation D1268 pp. 2004

# Design and Development of Accelerometers and



## **Tutorial 2B**

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## **Presentation Outline**

- Inertial Sensor Design Approach
- Product Improvements
- Applications
- Syroscope Design & Applications
- Conclusions



## *i*MEMS<sup>®</sup> Technology

## F=MA \*Acceleration can be measured using a simple mass/spring system.

- Force = Mass \* Acceleration
- Force = Displacement \* Spring Constant
- So Displacement = Mass \* Acceleration / Spring Constant





## *i*MEMS<sup>®</sup> Technology

## Sensor Principle: Differential Capacitive Sensing

- Use Silicon to make the spring and mass, and add fingers to make a variable differential capacitor
- Measure change in displacement by measuring change in differential capacitance





## ADI Accelerometers: Key Dimensions Interesting Facts

- \* 0.1 pF per side for the differential capacitor
- 20 zF (10-21 F) smallest detectable capacitance change
- \* 2.5 pm minimum detectable beam deflection (one tenth of an atomic diameter)



## *i*MEMS<sup>®</sup> **Technology** Capacitance to Voltage Conversion





## **Design Evolution ADXL50 (1993)**

## Circuit architecture

### Closed loop

- Concerns about polysilicon lead to force feedback design
- 0.6 V p-p complimentary modulation of differential capacitors
- Resistive biasing/FB (3 MΩ)

## MEMS design

- Dielectric under structure
- Anchors at periphery
- Beam not centered or symmetric





## **Design Evolution ADXL76 (1996)**

## Circuit architecture

### Open loop

- Polysilicon robustness now confirmed
- Full supply complimentary clocks
- Reduced die size
- Ratiometric
- Switched cap filter
- Switch biasing

## MEMS Design

- Conductor under structure
- Anchors on axis
- Beam centered & symmetric
  - Better offsets & tempco's





## **Design Evolution ADXL78 (2002)**

## Circuit architecture

#### Closed loop

- Overload performance pushed design back to feedback
- Servo complimentary clock amplitude
- Differential architecture
  Ratiometric & EMI resistant

## MEMS Design

- Two structures
- Conductor under structure
- Two springs/structure
- Robust to process variations
  Beam centered & symmetric

## Layout

Compact!









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	ADXL50	ADXL76	ADXL78	ADXL40	
	(1993)	(1996)	(2002)	(2004)	
Die Area	10.8	5.4	2.7	2.5	mm <sup>2</sup>
MEMS Area	0.43	0.38	0.27	0.22	mm <sup>2</sup>
% MEMS	4.0%	7.0%	10%	8.8%	
C <sub>s</sub>	100	100	40	160	fF
f <sub>o</sub>	25.0	24.5	24.5	12.5	kHz
Noise	4.0	1.0	1.0	1.0	mgee/ rt.hz
Offset	3.0	1.0	0.5	0.5	gee



#### Design Example: ADXL203 50 mg accurate, +/- 1.7 g, 2 axis XL



#### Problem:

How do we get a 10x improvement in null accuracy with minimal investment?

### Solution:

- Start with ADXL202 platform and make minimal changes
  - Structure
  - Electronics



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# Move anchors towards center of die Modeling & experiment verification Lower resonant frequency (10 kHz -> 5.5 kHz)

Use 4 µm polysilicon



## **ADXL203 Highlights**

- Culmination of 15 years of learning
  - Process, structure design, electronics, and packaging
- Typical 50 mg absolute accuracy over temperature, -40 to 125C
  - Measure absolute tilt to 3 degrees over temp
  - Resolve tilt changes to 0.01 degrees (1 mm over 100 m)
- Minimalist circuitry
  - For small size, thus low cost
    Low noise (110 µg/rt Hz.)
    Low drift
- Small 5 x 5 x 2 mm LCC package enabled by integration

## \* Details:

- Sensitivity
  - \* 8.2nm/g
- Resolution
  - \* 1Hz BW -> 800fm (Gyro 16 fm)
  - 100 fF -> 50zF (Gyro 12 zF)
- Offset
  - \* 0.05 g -> 4 Å (250 ppm)



Zero g vs. Temperature XL203 Characterization Lot 74990 Group B



5 degrees per minute going down, 10 degrees per minute going up

## **Interesting Applications**

- Air Bags
- Gesture Recognition
- Security
- Tilt Correction
- GPS Inertial Ref
- Toys Sports
- Vibration Sense
- Projector Keystone



"There are 1.6 MEMS devices per person in use today in the U.S. and the number is expected to grow to nearly 5 devices per person by 2004.

### **—MEMS Industry Group**







- •Air Bag Systems
- Navigation Systems
- •Car Alarms
- Vehicle Dynamic
  Control Systems
- Rollover Safety
  Systems







## ADI Sensors Used in Consumer and Industrial Products and Applications

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## **Blood Pressure Monitor**

## Company: OMRON

Product: Portable Blood
 Pressure
 Monitoring
 Device

- ADI Inside: ADXL311JE
- Function: Tilt Sensing
  - Measures forearm angle to ensure correct positioning of the wrist (at heart level)
  - Results in higher blood pressure measurement accuracy





## **Developing Applications Motion Sensing in Smart Handhelds**

- Tilt-sensing and motion recognition for handheld devices
- Intuitive spatial browsing on small screen devices
- Orientation and location detection for mobile phones







## *i*MEMS<sup>®</sup> Technology For Handhelds

**Application Ideas** 

## Situational Awareness

Enables optimization of phone features and functions based on the detection of

## environmental context, e.g.:

- \*Turns off display when phone is held at ear level
- Turns off vibrating mode when phone is not carried or held (not moving)
- Automatically activates pedometer function when walking motion is recognized
- Automatically selects portrait or landscape display orientation for picture taking or gaming
- Manages incoming calls based on user's activity level



## *i*MEMS<sup>®</sup> Technology For Handhelds

Large Document Panning and Zooming

Enables intuitive display control of large documents (e.g. maps) through tilt or inertial sensing

## Single-Handed Operation

Enables one hand operation of simple functions

## Data Entry/Selection

Enables menu and cursor control through tilt sensing and motion detection

## Intuitive Gaming

Enhances gaming experience by providing intuitive, button-less control of gaming action

Electronic Compass Tilt-Compensation











## **Cellular Phone/Pedometer**

- Company: FUJITSU
- Product: DoCoMo Cellular Phone for Japanese Market
- ADI Inside: ADXL311JE
- Function: Motion Sensing for Pedometer Function
  - Displays number of steps walked
  - Displays distance walked based on stride input
  - Displays calories expanded based on user weight input









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# **Pedometers**



#### Pedometer model SDM [ Tailwind and SDM Triax 100 Company: Nike, Inc. ADI Inside: iMEMS<sup>®</sup> ADXL78 and ADXL278 accelerometers

Function: Shock, tilt and inertial sensing for foot motion measurements resulting in accurate speed and distance information





# **Laptop Security**



### Anti-Theft<sup>™</sup> PCMCIA Card for Laptop Computers Company: Caveo Technology ADI Inside: iMEMS<sup>®</sup> ADXL202E accelerometer

Function: Inertial and tilt measurement for security perimeter and motion password setting





Game Boy<sup>®</sup> Advance with Kirby Tilt-n-Tumble<sup>™</sup> and Happy Panechu<sup>™</sup> Company: Nintendo ADI Inside: iMEMS<sup>®</sup> ADXL202 and ADXL202E accelerometers

Function: Tilt measurement resulting in intuitive game feature control





## MEMS in Personal Communications Intel Developers Conf.

## **Future Potential Uses of MEMS**



Antennas Color bi-stable display Micro-switches **Tunable capacitors** and inductors **Tunable filters** 

**Directional microphone** 



## **Wireless Buildings**

이 나는 것 같이 많이 많이 했다.





## **Integrated Micromachined Gyro**

Single Chip Rate Sensor 5V Operation Std Atmosphere 150 deg per second Self-Test 0.03 deg/sec/sqrt hz Compensated 5%

Lessons Learned In Accelerometer Development of Meso Structures Detecting Nano dimensions now applied to sub picodimensions

# Single Chip





## **iMEMS Gyro Sensor**

18312185 I M - M





## Coriolis Accel Full Scale Deflection 0.3 Nanometers Quadrature Rejection 1 ppm



Design Issues: Aerodynamics, Shock, Vibration, Thermal

DEVIDS



## Simplified Gyro Blockdiagram

1317 S. 174 - 7





## Gyro Packaging: in Vacuum or Air ?







## **Gyro Structure**

### Separated Accelerometer and Resonator





## **Electronic Design and Mechanical Design Interdependent**

15110 255 J - N - P



Functional Block Diagram





## **Gyro - Root Allan Variance**



#### Seconds

$$\sigma(\tau) = \sqrt{\frac{1}{2 \cdot (m-1)}} \cdot \frac{m-1}{\sum_{i=1}^{m-1} (y(i+1) - y(i))^2} \text{ for } m \text{ successitve } y(i) \text{ averaged}$$



## **Automotive Gyroscope Markets**

## Vehicle Dynamic Control

Interaction between anti-lock brake, electronic brakeforce distribution, traction control, and active yaw control systems to achieve dynamic stability

## Rollover

Extension of airbag safety systems for SUVs, vans, pickup trucks, and high-end vehicles

## Navigation

 Provide additional real-time location input and directions when GPS satellites are not available.











- Flight Controls/Training Systems
  - Unmanned aircrafts
  - Supplement to flight dynamic co
  - Supplement to GPS Guidance
- Robotics
  - Industrial robots
  - Toy Robots
- Weapon Systems
  - Smart Artillery Shells
  - Missile Guidance
- Platform stabilization
  - Camera
  - Machinery
  - Wheelchair stabilization
- Computer/Consum
  - Input devices
  - Handheld GPS









## **Conclusions**

- Inertial Sensor Designs are Mechanical Structures of Mass Supported by Springs
- Inertial Forces on the Mass Result in Displacement that is Sensed Capacitively
- New Trends in Applications for Motion Detection are Occuring in Hand-held Devices and Portable Devices
- Gyroscopes Vibrate an Accelerometer and Measure Coriolis Acceleration that Indicates Angular Rate





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## **Questions Please**